

基础物理Ⅱ固体理论导引

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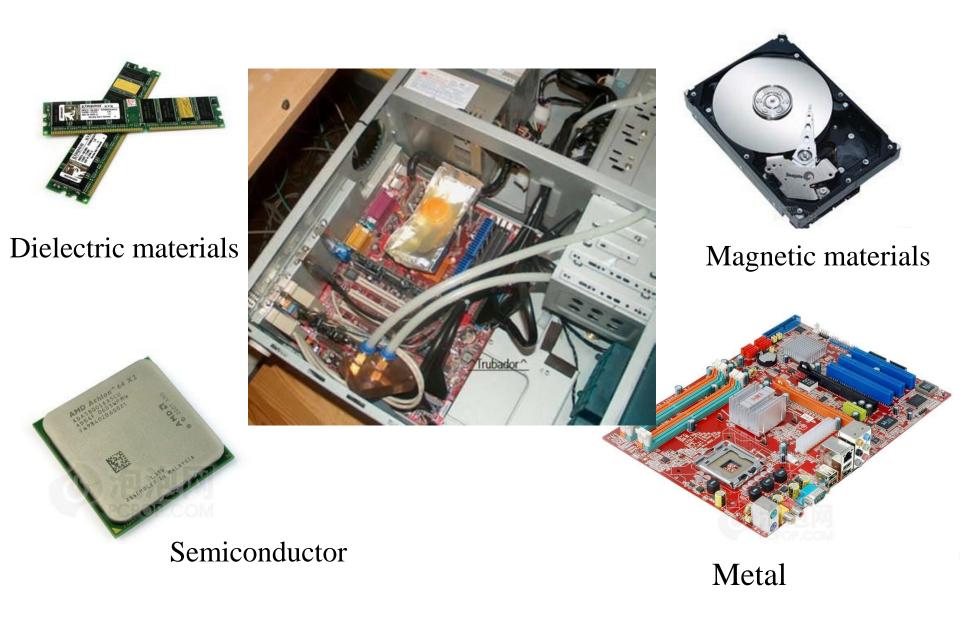
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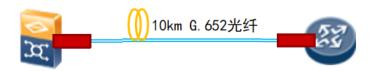
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What can we get from solid state physics?



What can we get from solid state physics?

5G communication network



Laser, detector, and multiplexer chips







AI chips: new architecture, new materials



Wearable chips:





Chapter 6 Electronic Properties of Semiconductors

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- 1. Intrinsic semiconductors (本征半导体)
- 2. Extrinsic semiconductors (非本征半导体) and PN junction (PN结)



Silicon is the most important semiconductor in today's electronics SOURCE: Courtesy of IBM

Typical Semiconductors



GaAs ingots and wafers. GaAs is used in high speed electronic devices, and optoelectronics.

|SOURCE: Courtesy of Sumitomo Electric Industries, Ltd.

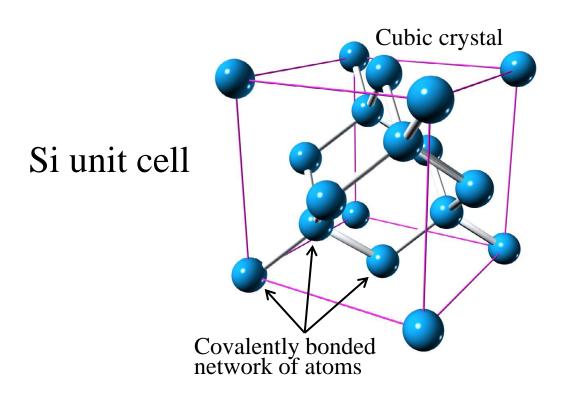


200 mm and 300 mm Si wafers.

|SOURCE: Courtesy of MEMC, Electronic Materials, Inc.

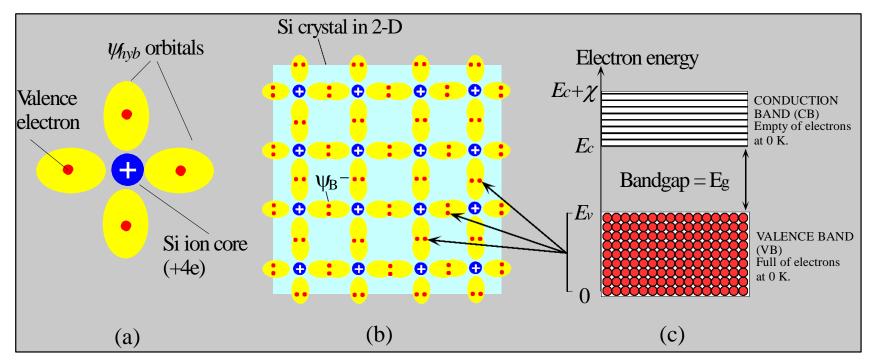
Crystal structure of Si

Intrinsic semiconductors (本征半导体) are perfect semiconductor crystals without any defects or impurities.



Each Si atom is connected to four neighbors through the formation of covalent bonds. Each bond holds two electrons that are shared by the two Si atoms.

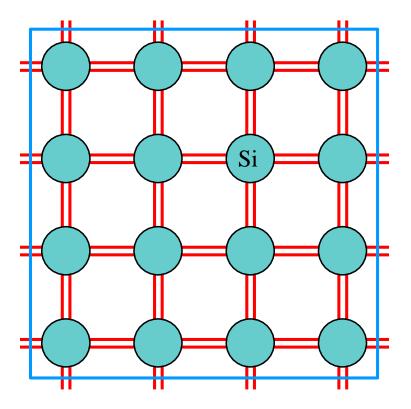
Silicon crystal and energy band diagram



(a) A simplified two dimensional illustration of a Si atom with four hybrid orbitals, ψ_{hyb} . Each orbital has one electron. (b) A simplified two dimensional view of a region of the Si crystal showing covalent bonds. (c) The energy band diagram at absolute zero of temperature.

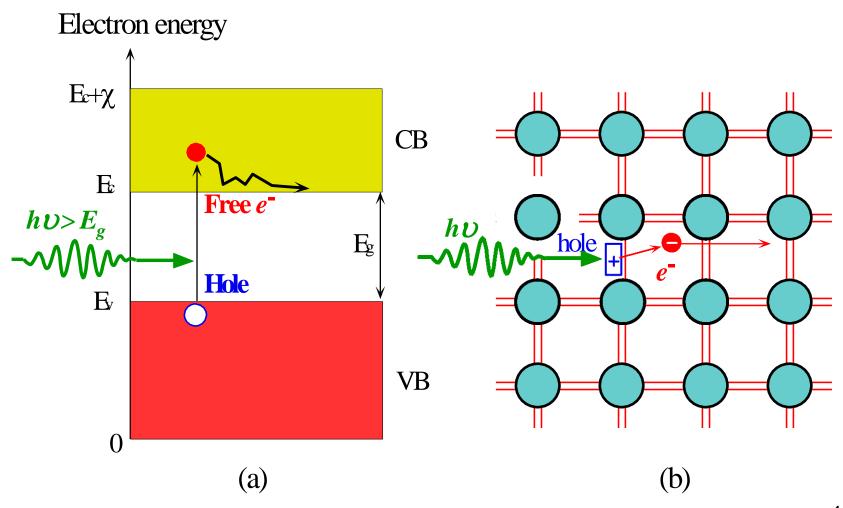
 E_g = energy gap (bandgap); E_v = top of the VB; E_c = bottom of the CB χ = electron affinity; E_g : 能带间隙 (带隙); E_v : 价带项; E_c : 导带底; χ : 电子亲和能

Insulator, Conductor, Semiconductor



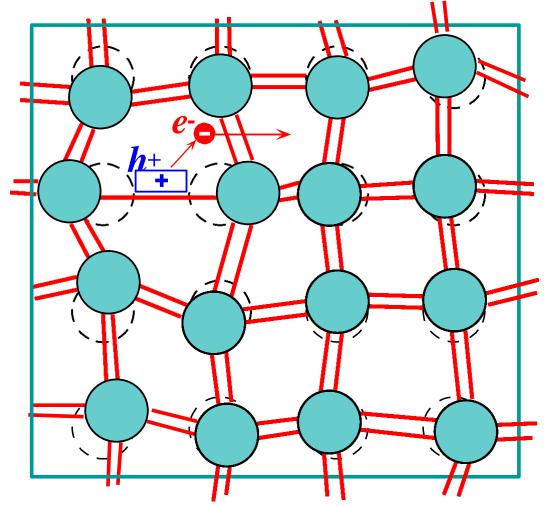
A two dimensional pictorial view of the Si crystal showing covalent bonds as two lines where each line is a valence electron.

Conduction electron due to optical excitation



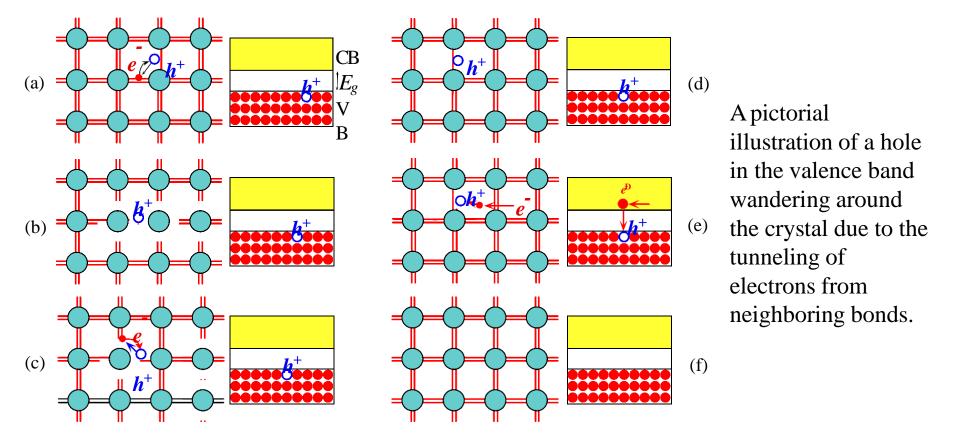
- (a) A photon with an energy greater than $E_{\rm g}$ can excite an electron from the VB to the CB.
- (b) When a photon breaks a Si-Si bond, a free **electron** and a **hole** in the Si-Si bond is created.

Conduction electron due to thermal excitation



Due to thermal energy, in a certain region, the atoms, at some instant, may be moving in such a way that a bond becomes overstretched.

Thermal vibrations of atoms can break bonds and thereby create electron-hole pairs.

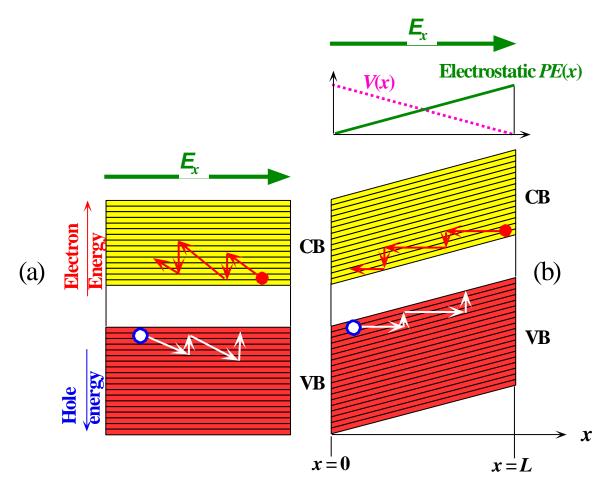


Recombination: When a wandering electron in the CB meets a hole in the VB, the electron has found an empty state of lower energy and therefore occupies the hole.

The excess energy of the electron falling from CB to VB is emitted as a photon, in GaAs and ZnO.

In Si and Ge, the excess energy is lost as lattice vibration (heat).

Conductivity(电导率) in semiconductors



When an electric field is applied, electrons in the CB and holes in the VB can drift (漂移运动)and contribute to the conductivity.

- (a) A simplified illustration of drift in E_{χ} .
- (b) Applied field bends the energy bands, since the electrostatic PE of the electron is -eV(x) and V(x) decreases in the direction of E_X whereas PE increases.

The current density J (漂移电流浓度):

$$J = env_{de} + epv_{dh}$$

Where n is the concentration of electrons in the CB, p is the hole concentration in the VB. n = 导带中的电子浓度,p = 价带中的空穴浓度.

漂移速度:

$$v_{de} = \mu_e E_x \cdots and \cdots v_{dh} = \mu_h E_x$$

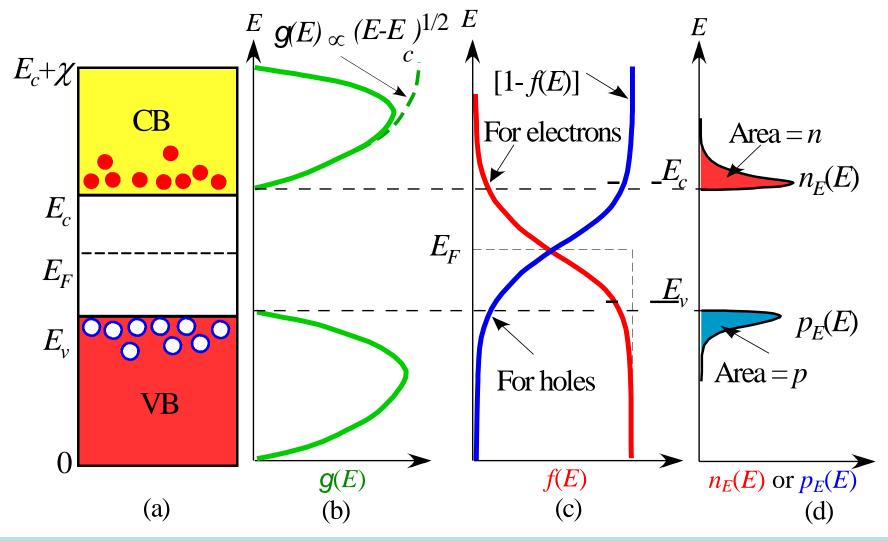
迁移率:

$$\mu_e = \frac{e \, \tau_e}{m_e^*} \cdots and \cdots \mu_h = \frac{e \, \tau_e}{m_h^*}$$

 τ is the mean free time between scattering events, m^* effective mass

The conductivity of a semiconductor:

$$\sigma = en\mu_e + ep\mu_h$$



- (a) Energy band diagram.
- (b) **Density of states** *g(E)*: number of states per unit energy per unit volume.
- (c) **Fermi-Dirac probability function** *f(E)*: probability of occupancy of a state.
- (d) Carrier distributions $n_E(E)$: the product of g(E) and f(E) is the energy density of electrons in the CB (number of electrons per unit energy per unit volume). The area under $n_E(E)$ vs. E is the electron concentration in the CB.

 $g_{cb}(E)$ is the density of states in the CB. The actual number of electrons per unit energy per unit volume $n_E(E)$ in the CB:

$$n_E dE = g_{cb}(E) f(E) dE$$

The electron concentration (number of electrons per unit volume):

$$n = \int_{E_c}^{E_c + \chi} n_E(E) dE = \int_{E_c}^{E_c + \chi} g_{cb}(E) f(E) dE$$

Assume that $(E_c-E_F) >> kT$:

$$f(E) \approx \exp[-(E - E_F)/kT]$$

Replacing Fermi-Dirac statistics by Boltzmann statistics assuming that the number of electrons in the CB is far less than the number of states in this band.

From
$$g_{cb}(E) = \frac{(8\pi\sqrt{2})m_e^{*3/2}}{h^3} (E - E_c)^{1/2}$$

$$\Rightarrow n \approx \frac{(\pi 8\sqrt{2})m_e^{*3/2}}{h^3} \int_{E_c}^{\infty} (E - E_c)^{1/2} \exp[-\frac{E - E_F}{kT}] dE$$

The solution is:

$$n \approx N_c \exp[-\frac{E_c - E_F}{kT}]$$

Where
$$N_c = 2 \left(\frac{2\pi m_e^* kT}{h^2} \right)^{3/2}$$

 $N_{\rm c}$ is a temperature-dependent constant, called the effective density of states at the CB edge.

We can carry out a similar analysis for the concentration of holes in the VB.

$$p = \int_{0}^{E_{v}} p_{E} dE = \int_{0}^{E_{v}} g_{vb}(E)[1 - f(E)] dE$$

With the assumption that E_F is a few kT above E_v, the integration simplifies to

$$p = N_v \exp\left[-\frac{(E_F - E_v)}{kT}\right]$$

Where N_v is the effective density of states at the VB edge.

$$N_{v} = 2 \left(\frac{2\pi m_{h}^{*} kT}{h^{2}} \right)^{3/2}$$

Important Equations for Intrinsic Semiconductors

$$n = N_c \exp\left[-\frac{E_c - E_F}{kT}\right]$$

$$E_F$$

$$E_F$$

$$E_F$$

$$VB$$

$$p = N_v \exp\left[-\frac{E_F - E_v}{kT}\right]$$

In intrinsic semiconductor, the numbers of electron and hole are the same (n=p), as they are generated in pair.

The product is a constant determined by the band gap.

$$np = n_i^2 = N_c N_v \exp\left(-\frac{E_g}{kT}\right)$$

n_i, the intrinsic concentration (本征载流子浓度)

Fermi levels

We first consider an intrinsic semiconductor, n=p=n_i.

$$N_{v} \exp \left[-\frac{E_{Fi} - E_{v}}{kT}\right] = \left(N_{c} N_{v}\right)^{1/2} \exp \left(-\frac{E_{g}}{2kT}\right)$$

If $m_e^* = m_h^*$:

$$\Rightarrow E_{Fi} = E_v + \frac{1}{2}E_g$$

 E_{Fi} is right in the middle of the energy gap. Normally, the Fermi level will be slightly down from the midgap by an amount of $\frac{3}{4}$ kTln(m_e^*/m_h^*).

Fermi levels

In a n-type semiconductor, n > p (for example through doping), the Fermi level must be closer to E_c than E_v .

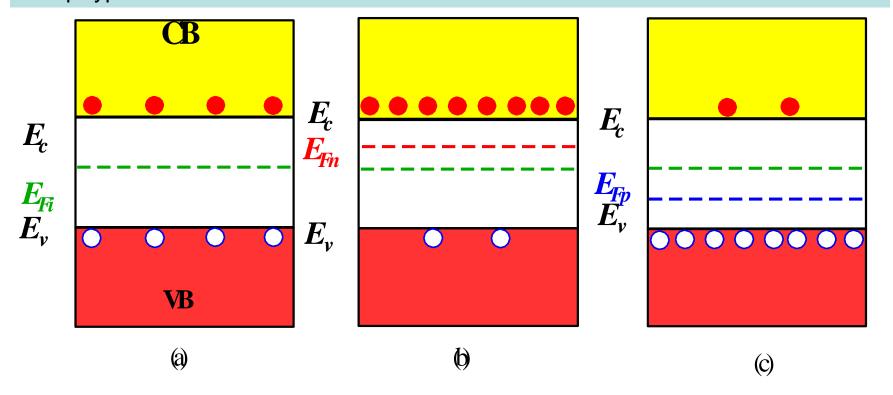
$$E_c - E_F < E_F - E_v$$

In a p-type semiconductor (p > n), the Fermi level must be closer to E_v than to E_c .

$$E_c - E_F > E_F - E_v$$

E_F is a material property.

The general band diagrams with the appropriate Fermi levels for intrinsic, n-type and p-type semiconductors.



Energy band diagrams for (a) intrinsic (b) n-type and (c) p-type semiconductors. In all cases, $np = n_i^2$

$$n = N_c \exp\left[-\frac{E_c - E_F}{kT}\right]$$
 $p = N_v \exp\left[-\frac{(E_F - E_v)}{kT}\right]$

Table 5.1 Selected typical properties of Ge, Si, and GaAs at 300 K

	E_g (eV)	χ (eV)	N_c (cm ⁻³)	N_v (cm ⁻³)	$\begin{array}{c} n_i \\ ({\rm cm^{-3}}) \end{array}$	$({\rm cm^2~V^{-1}~s^{-1}})$	$({\rm cm}^2~{\rm V}^{-1}~{\rm s}^{-1})$	m_e^*/m_e	m_h^*/m_e	ε_r
Ge	0.66	4.13	1.04×10^{19}	6.0×10^{18}	2.3×10^{13}	3900	1900	0.12 <i>a</i> 0.56 <i>b</i>	0.23 <i>a</i> 0.40 <i>b</i>	16
Si	1.10	4.01	2.8×10^{19}	1.2×10^{19}	1.0×10^{10}	1350	450	0.26 <i>a</i> 1.08 <i>b</i>	0.38 <i>a</i> 0.60 <i>b</i>	11.9
GaAs	1.42	4.07	4.7×10^{17}	7×10^{18}	2.1×10^{6}	8500	400	0.067 <i>a</i> , <i>b</i>	0.40 <i>a</i> 0.50 <i>b</i>	13.1

NOTE: Effective mass related to conductivity (labeled a) is different than that for density of states (labeled b). In numerous textbooks, n_i is taken as 1.45×10^{10} cm⁻³ and is therefore the most widely used value of n_i for Si, though the correct value is actually 1.0×10^{10} cm⁻³. (M. A. Green, J. Appl. Phys., 67, 2944, 1990.)

$$g_{cb}(E) = \frac{(\pi 8\sqrt{2})m_e^{*3/2}}{h^3}(E - E_c)^{1/2}$$

思考: 宽禁带半导体/第三代半导体

Example (intrinsic concentration and conductivity of Si): Given that the density of states related effective masses of electrons and holes in Si are approximately 1.08m_e and 0.60m_e, respectively, and the electron and hole drift nobilities at room temperature are 1350 and 450 cm²V⁻¹s⁻¹, respectively, calculate the intrinsic concentration and intrinsic resistivity of Si.

$$N_c = 2\left(\frac{2\pi m_e^* kT}{h^2}\right)^{3/2} = 2\left[\frac{2\pi (1.08x9.1x10^{-31})x(1.38x10^{-23})x300}{(6.63x10^{-34})^2}\right]^{3/2} = 2.81x10^{25}m^{-3} = 2.81x10^{19}cm^{-3}$$

$$(6.63x10^{-34})^2$$

$$N_{v} = 2\left(\frac{2\pi m_{h}^{*}kT}{h^{2}}\right)^{3/2} = 1.16x10^{25}m^{-3} = 1.16x10^{19}cm^{-3}$$

The intrinsic concentration is:

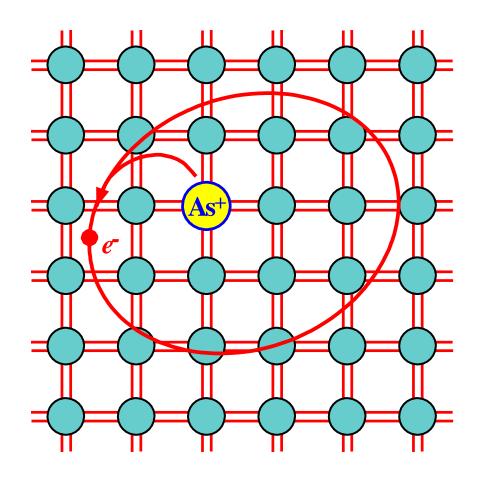
$$n_i = (N_c N_v)^{1/2} \exp\left(-\frac{E_g}{2kT}\right) = \left(2.81x10^{19} \cdot 1.16x10^{19}\right)^{1/2} \exp\left(-\frac{1.10 \cdot 1.6x10^{-19}}{2 \cdot 1.38x10^{-23} \cdot 300}\right) = \mathbf{1.0x10^{10} cm^{-3}}$$

The conductivity is

$$\sigma = en\mu_e + ep\mu_h = en_i(\mu_e + \mu_h) = 1.6x10^{-19} \cdot 1.0x10^{10}(1350 + 450) = 2.9x10^{-6} \Omega^{-1}cm^{-1}$$

$$\Rightarrow \rho = 1/\sigma = 3.5x10^5 \Omega cm$$

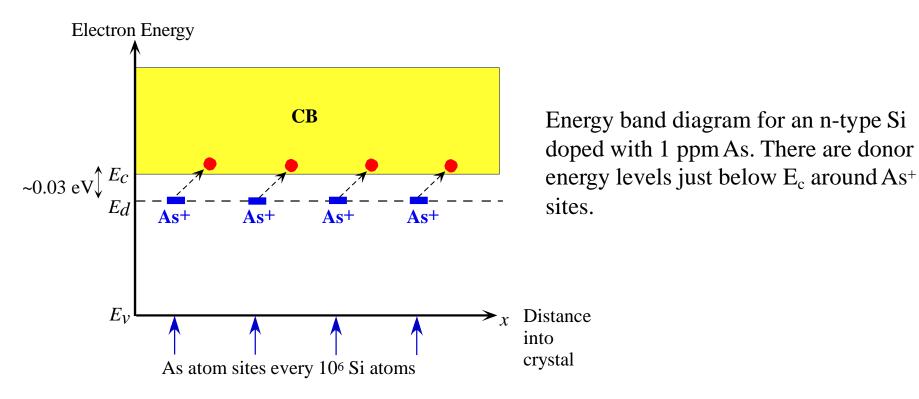
Extrinsic semiconductors, n-type



Consider what happens when small amount of a pentavalent (valence of 5) element from Group V, such as As or P, are introduced into a pure Si crystal (donor atoms).

Donor impurity

Arsenic doped Si crystal. The four valence electrons of As allow it to bond just like Si but the fifth electron is left orbiting the As site. The energy required to release to free fifth-electron into the CB is very small.



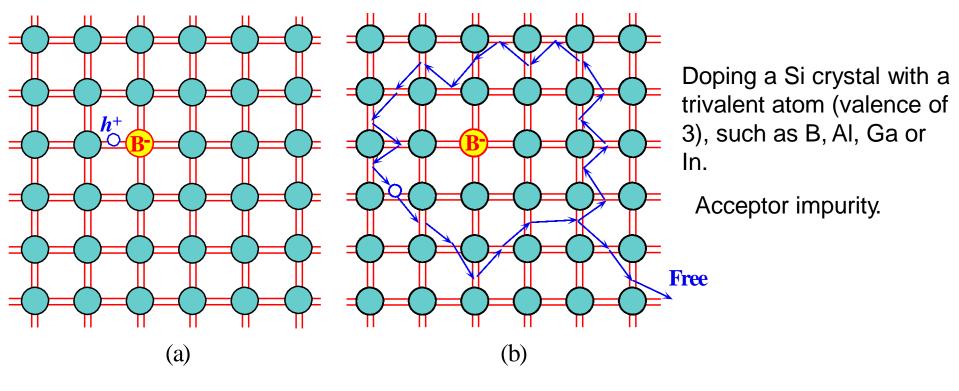
If the N_d is the donor atom concentration in the crystal, then provided that $N_d >> n_i$, at room temperature the electron concentration in the CB will be nearly equal to N_d , that is $n \approx N_d$.

 $p = \frac{ni^2}{N_d}$

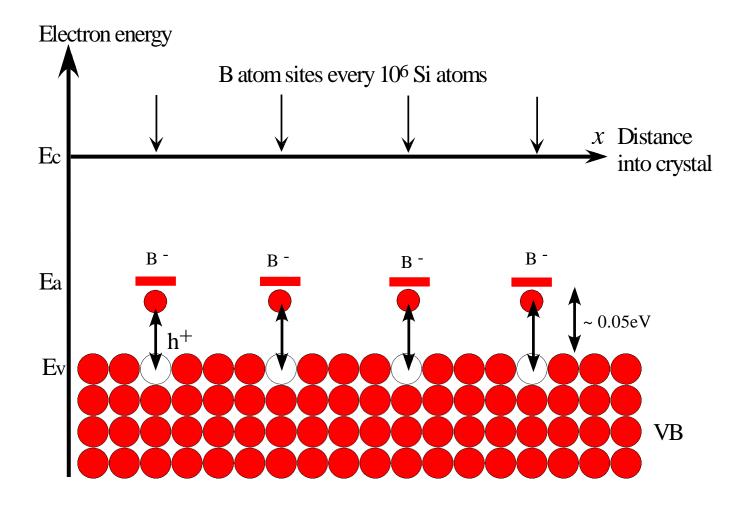
The conductivity σ

$$= eN_d \mu_e + e\left(\frac{n_i^2}{N_d}\right) \mu_h \approx eN_d \mu_e$$

Extrinsic semiconductors, p-type



Boron doped Si crystal. B has only three valence electrons. When it substitutes for a Si atom one of its bonds has an electron missing and therefore a hole as shown in (a). The hole orbits around the B⁻ site by the tunneling of electrons from neighboring bonds as shown in (b). Eventually, thermally vibrating Si atoms provides enough energy to free the hole from the B⁻ site into the VB as shown.



Energy band diagram for a p-type Si doped with 1 ppm B. There are acceptor energy levels just above E_V around B⁻ sites. These acceptor levels accept electrons from the VB and therefore create holes in the VB.

If the concentration of acceptor impurities N_a in the crystal is much greater than the intrinsic concentration n_i , then at room temperature all the acceptors would have been ionized and thus $p \approx N_a$. From $n = n_i^2/N_a$, which is much smaller than p:

The conductivity σ :

$$=eN_a\mu_h$$

Table 5.2 Examples of donor and acceptor ionization energies (eV) in Si

	Donors		Acceptors				
P	As	Sb	В	Al	Ga		
0.045	0.054	0.039	0.045	0.057	0.072		

Compensation doping

Compensation doping is a term used to describe the doping of a semiconductor with both donors and acceptors to control the properties.

1. More donors:

$$N_d - N_a >> n_i$$
 \Rightarrow $n = (N_d - N_a)$ and $p = \frac{n_i^2}{(N_d - N_a)}$

2. More acceptors:

$$N_a - N_d >> n_i$$
 \Rightarrow $p = (N_a - N_d)$ and $n = \frac{n_i^2}{(N_a - N_d)}$

Example (resistivity of intrinsic and doped Si): Find the resistance of a 1 cm³ pure silicon crystal cube. What is the resistance when the crystal is doped with arsenic if the doping is 1 in 10⁹, that is, 1 part per billion (ppb) (note that this doping corresponds to one foreigner living in China)? Given data: atomic concentration in silicon is 5×10^{22} cm⁻³, $n_i = 1.0 \times 10^{10}$ cm⁻³, $\mu_e = 1350$ cm²V⁻¹s⁻¹, and $\mu_h = 450$ cm²V⁻¹s⁻¹.

For the intrinsic case:

$$\sigma = en\mu_e + ep\mu_h = en_i(\mu_e + \mu_h) = 1.6x10^{-19} \cdot 1.0x10^{10} \cdot (1350 + 45) = 2.88x10^{-6}\Omega^{-1}cm^{-1}$$

Since L = 1cm, A = 1 cm²:
$$R = L/A\sigma = 3.47 \times 10^5 \Omega = 347 k\Omega$$

When the crystal is doped with 1 in 109:

$$N_d = \frac{N_{Si}}{10^9} = \frac{5x10^{22}}{10^9} = 5x10^{13} cm^{-3}$$

At room temperature, all the donors are ionized:

$$n = N_d = 5x10^{13} cm^{-3}$$

The hole concentration is:

$$p = \frac{n_i^2}{N_d} = \frac{(1.0x10^{10})^2}{5x10^{13}} = 2.0x10^6 cm^{-3} << n_i$$

$$\Rightarrow \sigma = en\mu = 1.6x10^{-19} \cdot 5x10^{13} \cdot 1350 = 1.08x10^{-2}$$

$$\Omega^{-1}cm^{-1}$$

$$\Rightarrow R = L/A\sigma = 92.6\Omega$$

If doping with boron instead of arsenic (a p-type semiconductor with the same level of doping):

$$\sigma = ep\mu_h = 1.6x10^{-19} \cdot 5x10^{13} \cdot 450 = 3.6x10^{-3} \Omega^{-1} cm^{-1}$$

$$\Rightarrow R = L/A\sigma = 278\Omega$$

Example (the Fermi level in n- and p-type Si): An n-type Si wafer has been doped uniformly with 10^{16} antimony (Sb) atoms cm⁻³. Calculate the position of the Fermi energy with respect to the Fermi energy E_{Fi} in intrinsic Si. The above n-type Si sample is further doped with $2x10^{17}$ boron atoms cm⁻³. Calculate the position of the Fermi energy with respect to the Fermi energy E_{Fi} in intrinsic Si (Assume T = 300K and kT = 0.0259 eV).

Sb gives n-type doping with $N_d = 10^{16} \text{cm}^{-3}$, and $N_d >> n_i \ (=10^{10} \text{ cm}^{-3})$

$$\Rightarrow$$
 n = N_d = 10¹⁶ cm⁻³

$$n_i = N_c \exp \left[-\frac{E_c - E_{Fi}}{kT} \right]$$

$$n = N_c \exp \left[-\frac{E_c - E_{Fn}}{kT} \right] = N_d$$

$$\Rightarrow$$

$$\frac{N_d}{n_i} = \exp\left[\frac{E_{Fn} - E_{Fi}}{kT}\right]$$

$$\Rightarrow$$

$$E_{Fn} - E_{Fi} = kT \ln \left(\frac{N_d}{n_i} \right) = 0.0259 \ln \left(\frac{10^{16}}{1.0 \times 10^{10}} \right) = 0.36 eV$$

The semiconductor is compensation doped and compensation converts the semiconductor to p=type Si.

$$p = N_a - N_d = (2x10^{17} - 10^{16}) = 1.9x10^{17} cm^{-3}$$

For intrinsic Si:

$$n_i = N_v \exp \left[-\frac{E_{Fi} - E_v}{kT} \right]$$

For doped p-type Si:

$$p = N_{v} \exp \left[-\frac{E_{Fp} - E_{v}}{kT} \right] = N_{a} - N_{d}$$

$$\Rightarrow \frac{p}{n_i} = \exp \left[-\frac{E_{Fp} - E_{Fi}}{kT} \right]$$

$$\Rightarrow E_{Fp} - E_{Fi} = -kT \ln \left(\frac{p}{n_i}\right) = -0.0259 \ln \left(\frac{1.9x10^{17}}{1.0x10^{10}}\right) = -0.43eV$$